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(54) **SEMICONDUCTOR VARIABLE-CAPACITY ELEMENT**

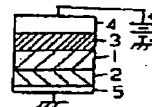
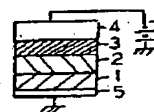
(57) Abstract:

**PURPOSE:** To attain a large variation in capacity and a large performance index and also to make a leak current small by forming an N-type semiconductor layer and others sequentially on a P-type semiconductor layer or by forming the P-type semiconductor layer and others sequentially on the N-type semiconductor layer.

**CONSTITUTION:** After an N-type semiconductor layer 2, an insulating film 3 and an electrode 4 are formed on a P-type semiconductor layer 1, an ohmic electrode 5 is formed on the rear side of a crystal. When the layer 1 is grounded and a negative voltage is impressed on the electrode 4, the impressed voltage makes the layer 1 inject holes into the layer 2 and the injected holes reach an interface between the layer 2 and the film 3 and give a capacity value. When the negative voltage is increased, the number of holes increases exponentially and the capacity value of a variable-capacity element increases to a large extent. When the electrode 4 is set at 0V, the surface of the film 2 on the film 3 side turns to have a flat energy band structure and the capacity value of the variable-capacity element becomes minimum. In the case when the layer 1, the film 3 and the electrode 4 are formed on the layer 2 and a positive voltage is impressed on the electrode 4, the capacity

value of the variable-capacity element becomes minimum as well. According to this constitution, a small variation in capacity and a large performance index are attained and a leak current can be made small.

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